ISC Audits & Reviews SC Summary (Nov 19, 2026)

Doc.	Title	Vote
7366;	New Auxiliary Information Document: Report on Closing Metrologies Gaps for post-CMP Cleaning Solutions;	Passed
7380B-LI1;	Clarify how XY coordinates and Location ID are used;	Passed
7418;	Reapproval of SEMI M20-0215 (Reapproved 0421) Practice for Establishing a Wafer Coordinate System;	Passed
7467;	New Auxiliary Information Document, Sub-50 nm Liquid Filter Retention in Ultrapure Water: Comparison and Application of SEMI C79, C82, and C89;	Passed
7470;	Revision of SEMI S5, Safety Guideline for Sizing and Identifying Flow Limiting Devices for Gases;	Passed
7471;	Revision to SEMI C98-1219, Guide for Chemical Mechanical Planarization (CMP) Particle Size Distribution (PSD) Measurement and Reporting Used in Semiconductor Manufacturing;	Passed
7485;	Revision to SEMI S14-0521 - Safety Guideline for Fire Risk Assessment and Mitigation for Semiconductor Manufacturing Equipment (Fire Protection) ;	Passed
7488;	Update issues raised by TF members	Passed
7491-LI1;	Address issues with Well-Known Names and Compliance Statement;	Passed
7492-LI1;	Address issues with Well-Known Names;	Passed
7493-LI2;	Clarify Load Port and Internal Buffer Equipment Expectations;	Passed
7493-LI3;	New SV to Report CarrierID at a Load Port;	Passed
7494;	Withdrawal of SEMI E188-0222 - Specification for Malware Free Equipment Integration;	Passed
R7315;	Ratification Ballot - New Standard: Specification for Property Requirements of Finger Pastes for TOPCon Cell with Laser Assisted Firing Process;	Passed
SEMI S2-0724E	Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Type 2 Editorial Changes)	Passed

For more information, please contact the SEMI Standards Engineer/Coordinator.
(http://www.semi.org/standards/contacts) nearest you.

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Nivember 19, 2026